

SUPPLEMENTARY EUROPEAN SEARCH REPORT

Application Number
EP 15 76 3811

DOCUMENTS CONSIDERED TO BE RELEVANT			
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (IPC)
X	US 2012/069509 A1 (IKEGUCHI TAZOH [JP]) 22 March 2012 (2012-03-22)	1,6,7,11	INV. G02F1/1337
A	* abstract * * figures 2,7 * * paragraph [0041] * * paragraph [0049] - paragraph [0050] * * paragraph [0059] - paragraph [0060] *	2-5,8-10	G02F1/1333
X	CN 101 211 068 A (QUNKANG TECH SHENZHEN CO LTD [CN]) 2 July 2008 (2008-07-02)	1,6,7,11	
A	* the whole document *	2-5,8-10	
			TECHNICAL FIELDS SEARCHED (IPC)
			G02F
The supplementary search report has been based on the last set of claims valid and available at the start of the search.			
Place of search Munich		Date of completion of the search 11 April 2018	Examiner Sittler, Gilles
CATEGORY OF CITED DOCUMENTS X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document			

**ANNEX TO THE EUROPEAN SEARCH REPORT
ON EUROPEAN PATENT APPLICATION NO.**

EP 15 76 3811

This annex lists the patent family members relating to the patent documents cited in the above-mentioned European search report.
The members are as contained in the European Patent Office EDP file on
The European Patent Office is in no way liable for these particulars which are merely given for the purpose of information.

11-04-2018

Patent document cited in search report		Publication date	Patent family member(s)		Publication date
US 2012069509	A1	22-03-2012	US	2012069509 A1	22-03-2012
			WO	2010143543 A1	16-12-2010

CN 101211068	A	02-07-2008	NONE		

专利名称(译)	阵列基板，其制造方法和显示装置		
公开(公告)号	EP3200021A4	公开(公告)日	2018-05-23
申请号	EP2015763811	申请日	2015-05-21
[标]申请(专利权)人(译)	京东方科技集团股份有限公司 北京京东方光电科技有限公司		
申请(专利权)人(译)	京东方科技集团股份有限公司. 北京京东方光电科技有限公司.		
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IPC分类号	G02F1/1337		
CPC分类号	G02F1/133784 G02F1/133345 G02F1/133514 G02F1/134309 G02F1/136286 G02F2001/133792 G02F2201/121 G02F2201/123 G02F2201/50		
代理机构(译)	POTTER CLARKSON LLP		
优先权	201410505653.5 2014-09-26 CN		
其他公开文献	EP3200021B1 EP3200021A1		
外部链接	Espacenet		

摘要(译)

公开了一种阵列基板，制造阵列基板的方法和显示装置，用于消除在单元处理期间产生的白色Mura缺陷。该方法包括以下步骤：在基板上形成显示区域和非显示区域，电路接合区域布置在非显示区域内;通过构图工艺在显示区域内形成取向膜;通过图案化工艺形成至少在除电路接合区域之外的非显示区域的一部分中的透明保护层;通过摩擦压印工艺，在取向膜表面上形成多条具有相同取向的线，用于液晶分子的有序排列，其中透明保护层的表面高度小于或等于取向膜的表面高度。

DOCUMENTS CONSIDERED TO BE RELEVANT		Relevant to:	CLASSIFICATION OF THE APPLICATION (IPC)												
Category	Category of document with indication, where appropriate, of relevant passages	Relevant to:	CLASSIFICATION OF THE APPLICATION (IPC)												
X	US 2012/060599 A1 (HEDUCHI TAZOH [JP]) 22 March 2012 (2012-03-22) * Abstract *	1,6,7,11	INT.												
A	* Figures 2,7 * * paragraph [0041] * paragraph [0050] * * paragraph [0049] * paragraph [0060] *	2-5,8-10	G02F1/1337 G02F1/1333												
X	CN 101 211 068 A (QINKANG TECH SHENZHEN CO LTD [CN]) 2 July 2008 (2008-07-02) * the whole document * - - - -	1,6,7,11													
A		2-5,8-10													
The 3200021 search report has been drawn on the last day of the search.															
<table border="1"> <tr> <td>Place of search</td> <td>Munich</td> <td>Date of completion of the search</td> <td>11 April 2018</td> <td>Searcher</td> <td>Sittler, Gilles</td> </tr> <tr> <td colspan="6"> CATEGORY OF CITED DOCUMENTS: 1. Document cited for prior art. 2. Document cited for other reasons. 3. Document cited for other reasons. 4. Document cited for other reasons. 5. Document cited for other reasons. 6. Document cited for other reasons. 7. Document cited for other reasons. 8. Document cited for other reasons. 9. Document cited for other reasons. 10. Document cited for other reasons. </td> </tr> </table>				Place of search	Munich	Date of completion of the search	11 April 2018	Searcher	Sittler, Gilles	CATEGORY OF CITED DOCUMENTS: 1. Document cited for prior art. 2. Document cited for other reasons. 3. Document cited for other reasons. 4. Document cited for other reasons. 5. Document cited for other reasons. 6. Document cited for other reasons. 7. Document cited for other reasons. 8. Document cited for other reasons. 9. Document cited for other reasons. 10. Document cited for other reasons.					
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